

Title (en)
APPARATUS FOR TREATMENT OF A PROCESS GAS

Publication
EP 0299458 B1 19910508 (EN)

Application
EP 88111226 A 19880713

Priority
JP 17469587 A 19870715

Abstract (en)
[origin: EP0299458A2] The apparatus for treatment of a process gas comprises a vacuum pump provided with a heating portion (8) for preventing adhesion of reaction products on a discharge side (3) thereof.

IPC 1-7
F04D 17/16; F04D 19/04

IPC 8 full level
F04D 17/16 (2006.01); **F04D 19/04** (2006.01); **F04D 29/58** (2006.01); **F04D 29/70** (2006.01)

CPC (source: EP US)
F04D 17/168 (2013.01 - EP US); **F04D 19/046** (2013.01 - EP US); **F04D 29/582** (2013.01 - US); **F04D 29/584** (2013.01 - EP); **F05D 2250/52** (2013.01 - EP); **F05D 2260/607** (2013.01 - EP)

Cited by
EP1178217A3; DE19702456A1; DE19702456B4; US6629824B2

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DE FR

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EP 0299458 A2 19890118; EP 0299458 A3 19890405; EP 0299458 B1 19910508; DE 3862699 D1 19910613; JP H0525040 B2 19930409; JP S6419198 A 19890123; US 4904155 A 19900227

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EP 88111226 A 19880713; DE 3862699 T 19880713; JP 17469587 A 19870715; US 21788788 A 19880712